## **LISTING OF THE CLAIMS**

The following listing of claims will replace all prior versions and listings of claims in the application.

- 1. (Cancelled)
- 2. (Currently Amended) A method for forming a reflective reflector pattern comprising: forming a micropattern using an organometallic-containing compound through a photoreaction or thermal energy through the following steps:
- (a) coating the organometallic-containing compound on a substrate to form a thin film,
  - (b) exposing the thin film to light through a mask to decompose the organometallic-containing compound at exposed area and to induce a difference in solubility between the exposed and unexposed areas and developing the thin film to remove the organometallic-containing compound of the unexposed area, and
  - (c) reducing or oxidizing the exposed area to form a metal pattern or metal oxide pattern; and

growing crystal, using the pattern as a nucleus for growing crystal, by an electro or electroless Ag plating process.

3. (Currently Amended) A method for forming a reflective reflector pattern comprising: forming a micropattern using an organometallic-containing compound through a photoreaction or thermal energy through the following steps:

(a) forming a pattern using the organometallic-containing compound through soft

lithography or ink jet printing, and

(b) heating the pattern to decompose the organometallic-containing compound; and

growing crystal, using the pattern as a nucleus for growing crystal, by an electro or electroless Ag plating process.

- 4. (Original) The method according to claim 3, wherein the soft lithography is microcontact printing or micromolding in capillaries (MIMIC).
- 5. (Currently amended) The method according to claim 2 or 3, wherein the organometallic-containing compound is represented by the following formula 1:

$$M_m L_2 X_p$$
 (1)

wherein M is a metal; L is a ligand; X is a monovalent to trivalent anion; m is an interger from 1 to 10, and when m is 2 or more, each M may be different from the other; n is an integer from 0 to 60, and when n is 2 or more, each L may be different from the other; p is an integer from 0 to 60, and when p is 2 or more, each X may be different from the other; L may act as a ligand bonding two metals when two or more metals are used; and n and p are not simultaneously 0.

6. (Previously Presented) The method according to claim 5, wherein M is a late transition metal (IX~XII) selected from the group consisting of Co, Ni, Pd, Pt, Cu, Ag, Au, An and Ce, or A1.

- 7. (Previously Presented) The method according to claim 5, wherein L is a ligand selected from the group consisting of acetylacetonates, acetates, β-ketoiminates, β-diiminates, β-ketoesters, dialkyldithiocarbamates, carboxylates, oxalate, alkoxy ligands, pyridines, amines, diamines, arsines, diarsines, phosphines, diphosphines, arenas, carbonyl, imidazolylidene, ethylene, acetylene, aquo, thiocarbonyl, thioether and a derivative thereof.
- 8. (Previously Presented) The method according to claim 5, wherein X is an anion selected from the group consisting of halogen, hydroxy, cyanide  $(CN_3^-)$ , nitrite  $(NO_2^-)$ , nitrate  $(NO_2^-)$ , nitrate  $(NO_3^-)$ , nitrosyl  $(NO_3^-)$ , azide  $(N_4^-)$ , thiocyanate  $(NCS_3)$ , isothiocyanate  $(SCN_4^-)$ , tetraalkylborate  $(BR_4^-, R = methyl, ethyl or phenyl group)$ , tetrahaloborate  $(BX_4^-, X = F, Br)$ , hexafluorophosphate  $(PF_6^-)$ , triflate  $(CF_3SO_3^-)$ , tosylate  $(TS_3^-)$ , sulfate  $(SO_4^2^-)$ , and carbonate  $(CO_3^2^-)$ .
- 9. (Previously Presented) The method according to claim 6, wherein the organometallic-containing compound is a silver compound.
  - 10. (Cancelled)
  - 11. (Cancelled)
- 12. (Previously Presented) The method according to claim 5, wherein M is at least one transition metal, lanthanide or A1.

13. (New) The method according to claim 3, wherein the organometallic-containing compound is represented by the following formula 1:

$$M_m L_2 X_p$$
 (1)

wherein M is a metal; L is a ligand; X is a monovalent to trivalent anion; m is an interger from 1 to 10, and when m is 2 or more, each M may be different from the other; n is an integer from 0 to 60, and when n is 2 or more, each L may be different from the other; p is an integer from 0 to 60, and when p is 2 or more, each X may be different from the other; L may act as a ligand bonding two metals when two or more metals are used; and n and p are not simultaneously 0.